BERNOULLI CHUCK AND USE METHOD

Abstract

The present invention belongs to the technical field of semiconductor processing and cleaning, and specifically relates to a Bernoulli chuck and a use method. The Bernoulli chuck includes: a supporting seat which is rotatably arranged, a plurality of supporting posts being rotatably arranged on the top of the supporting seat, clamping posts being eccentrically arranged on the tops of the supporting posts, shifting plates being arranged on sidewalls of the supporting posts, and through shifting notches being formed in the shifting plates; a rotating seat which is coaxially arranged on the top of the supporting seat, shifting posts being arranged on the rotating seat and clamped in the shifting notches all the time; a plurality of elastic structures which are arranged between the bottom of the rotating seat and the top of the supporting seat and are configured to drive the rotating seat to rotate relative to the supporting seat if the supporting seat rotates at a variable speed and to drive the rotating seat return to an initial position if the supporting seat changes from variable-speed rotation to constant-speed rotation; and an adsorption assembly which is coaxially arranged on the supporting seat.

Fig 1.